

**Amendment and Response to Paper mailed 9/4/03**

Sir:

Thank you for your continued expedient examination of the present Application.

In response to the Office Action mailed 9/4/03, please amend the above application as follows:

**Statement of Claims Status**

Claims 18-33 are pending in the application.

Claims 18-33 are rejected.

**Summary of Response**

*Detailed Action*

Examiner States:

“The corrected or substitute drawings were received on Oct. 25, 2002. These drawings are not acceptable. The association of the added box in Fig. 3 with box element 13 is unclear.”

Examiner States:

“Claims 18-33 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention.

It is unclear what is meant by "capital goods" in line 2 of claim 18.

Examiner States:

Amendment and Response to Final Office Action mailed 9/4/03  
Filing date: 10/6/2000  
Serial No: 09/680,286 Art Unit: 2856  
Title: REMOTE MONITORING OF CRITICAL PARAMETERS FOR CALIBRATION OF  
MANUFACTURING EQUIPMENT AND FACILITIES

Date mailed: 11/9/2003  
Attorney Docket No. ENP-01

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“In line 3 it is unclear what is meant by "critical parameters related to chemical / material analysis techniques". I.e. how do they differ from measurements not related to such techniques?”

Examiner States:

“Claims 18-33 are rejected under 35 U.S.C. 103(a) as being unpatentable over Moslehi US 5,270,222 in view of (Renken et al US 5,967,661 or Melcher US 5,015,951).

Moslehi does not disclose attaching sensors, recording device and energy source to a surface of the capital good (semiconductor wafer) being monitored. However it is well known to incorporate such features into semiconductors and thus they obviously could have been in the system of Moslehi especially in view of the teaching of incorporation of sensors or sensing structure on material in either Renken et al (note especially Fig. 9) and Melcher. It is noted that temperature as monitored by Renken can be considered a critical parameter. Use of such element placement in Moslehi would have obviously eased measuring by avoid signal transmission delays, etc. The various electronic components and memory systems. etc. appear to be all well known of general utility and could thus obviously have been incorporated thereinto.”

Examiner States:

“Isolation from external hostile environments is a known expedient to protect the equipment and get more accurate measurements.”

Examiner States:

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**“One of ordinary skill would have been able to monitor in liquid environments since techniques for monitoring such environments appear to be well known.”**